Overview: Piezoelectricity

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Outline

- Department of Sensor Technology
- Basics
 - Piezoelectric effect
 - Piezoelectric equations
 - Piezoelectric materials

Finite Element Formulation

- Weak form
- Spatial and time discretization
- Solvers for the algebraic system of equations

Material parameter determination

- Experimental methods
- Invers scheme





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Location





Overview: Piezoelectricity

Basics

- Finite Element Formulation
- Material Parameter Determination



Piezoelectric Effect

• Direct effect (sensor)



Indirect effect (actuator)





Governing Equations

Constituitive equations

$$[\boldsymbol{\sigma}] = [\mathbf{c}^{E}][\mathbf{S}] - [\mathbf{e}]^{T}\mathbf{E}$$
$$\mathbf{D} = [\mathbf{e}][\mathbf{S}] + [\boldsymbol{\varepsilon}^{S}]\mathbf{E}$$



- **Piezoelectric materials** can be subdivided in the following three categories
 - Single crystals, like quartz
 - Piezoelectric ceramics like barium titanate or lead zirconate
 - **Polymers** like PVDF (polyvinylidenfluoride)

Tensors for 6mm Crystal Class



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Polarization / Strain versus Electric Field Intensity



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Coupled Equations (I)

Mechanical field (Navier's equation)

- u ... mechnaical displacement ... stress tensor σ ... strain tensor S f_V ... mechanical volume force
- Electrostatic field (Maxwell's equations)

 $\nabla \cdot \mathbf{D} = 0$ $\nabla \times \mathbf{E} = \mathbf{0} \Rightarrow \mathbf{E} = -\nabla V_{\mathbf{e}}$

D ... electric flux density $V_{\rm e}$... scalar electric potential ... electric field intensity

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Coupled Equations (II)

Constituitive equations

$$[\boldsymbol{\sigma}] = [\mathbf{c}^{E}][\mathbf{S}] - [\mathbf{e}]^{T}\mathbf{E}$$
$$\mathbf{D} = [\mathbf{e}][\mathbf{S}] + [\boldsymbol{\varepsilon}^{S}]\mathbf{E}$$

Coupled equations

$$\rho \ddot{\mathbf{u}} - \mathcal{B}^T \left([\mathbf{c}^E] \mathcal{B} \mathbf{u} + [\mathbf{e}]^T \nabla V_{\mathbf{e}} \right) = \mathbf{f}_{\mathbf{V}}$$
$$\nabla \cdot \left([\mathbf{e}] \mathcal{B} \mathbf{u} - [\varepsilon^{S}] \nabla V_{\mathbf{e}} \right) = \mathbf{0}$$

Boundary conditions



$$\mathbf{u} = 0 \text{ on } \Gamma_{e}^{u}$$

$$V_{e} = 0 \text{ on } \Gamma_{e}^{V}$$

$$\mathbf{n} \cdot [\boldsymbol{\sigma}] = 0 \text{ on } \Gamma_{n}^{\sigma}$$

$$\mathbf{n} \cdot \mathbf{D} = -\frac{q_{e}}{A} \text{ on } \Gamma_{n}^{D_{1}}$$

$$\mathbf{n} \cdot \mathbf{D} = 0 \text{ on } \Gamma_{n}^{D_{2}}$$

Finite Element Formulation (I)

• Weak form: Find $(\mathbf{u} \in \mathbf{H}_0^1, V_e \in H_0^1)$ such that

$$\int_{\Omega} \rho \mathbf{u}' \cdot \ddot{\mathbf{u}} \, \mathrm{d}\Omega + \int_{\Omega} (\mathcal{B}\mathbf{u}')^T [\mathbf{c}^E] \mathcal{B}\mathbf{u} \, \mathrm{d}\Omega + \int_{\Omega} (\mathcal{B}\mathbf{u}')^T [\mathbf{e}]^T \tilde{\mathcal{B}} V_{\mathbf{e}} \, \mathrm{d}\Omega = 0$$

$$\int_{\Omega} (\tilde{\mathcal{B}}\psi)^T \mathbf{e}(\mathcal{B}\mathbf{u}) \, \mathrm{d}\Omega - \int_{\Omega} (\tilde{\mathcal{B}}\psi)^T [\boldsymbol{\varepsilon}^S] \, \tilde{\mathcal{B}} V_{\mathbf{e}} \, \mathrm{d}\Omega = -\int_{\Gamma_n^{D_1}} \psi \frac{q_{\mathbf{e}}}{A} \, \mathrm{d}\Gamma$$

for any
$$(\mathbf{u}' \in \mathbf{H}_0^1, \psi \in H_0^1)$$

Spatial approximation

$$V_{\rm e} \approx V_{\rm e}^h = \sum_{a=1}^{n_{\rm n}} N_a V_{\rm ea}$$



Nodal shape function (local support)

$$\mathbf{u} \approx \mathbf{u}^{h} = \sum_{i=1}^{n_{d}} \sum_{a=1}^{n_{n}} N_{a} u_{ia} \mathbf{e}_{i} = \sum_{a=1}^{n_{n}} \mathbf{N}_{a} \mathbf{u}_{a} \quad ; \quad \mathbf{N}_{a} = \begin{pmatrix} N_{a} & 0 & 0 \\ 0 & N_{a} & 0 \\ 0 & 0 & N_{a} \end{pmatrix}$$



Finite Element Formulation (II)

Semidiscrete Galerkin formulation:

$$\begin{pmatrix} \mathbf{M}_{u} & \mathbf{0} \\ \mathbf{0} & \mathbf{0} \end{pmatrix} \begin{pmatrix} \frac{\ddot{u}}{\ddot{V}\mathbf{e}} \end{pmatrix} + \begin{pmatrix} \mathbf{C}_{u} & \mathbf{0} \\ \mathbf{0} & \mathbf{0} \end{pmatrix} \begin{pmatrix} \frac{\dot{u}}{\dot{V}\mathbf{e}} \end{pmatrix} + \begin{pmatrix} \mathbf{K}_{u} & \mathbf{K}_{uV} \\ \mathbf{K}_{uV}^{T} & -\mathbf{K}_{V} \end{pmatrix} \begin{pmatrix} \frac{u}{V\mathbf{e}} \end{pmatrix}$$
$$= \begin{pmatrix} \mathbf{0} \\ \frac{f_{q}} \end{pmatrix}$$

\mathbf{M}_{u}		mechanical mass matrix	\mathbf{K}_{uV}	 coupling matrix
\mathbf{C}_{u}	• • •	mechanical damping matrix	\mathbf{K}_V	 electric stiffness matrix
\mathbf{K}_{u}		mechanical stiffness matrix	f_{q}	 electric force vector
\underline{u}		mechanical displacement	$\overline{V_{e}}$	 electric scalar potential

• Introduced damping via Rayleigh model:

$$\mathbf{C}_u = lpha \mathbf{M}_u + eta \mathbf{K}_u$$
 $lpha$, eta ... damping coefficients



Finite Element Formulation (III)

• Time discretization: Newmark method

$$\underline{u}_{n+1} = \underline{u}_n + \Delta t \, \underline{\dot{u}}_n + \frac{\Delta t^2}{2} \left((1 - 2\beta_{\mathsf{H}}) \underline{\ddot{u}}_n + 2\beta_{\mathsf{H}} \underline{\ddot{u}}_{n+1} \right)$$

$$\underline{\dot{u}}_{n+1} = \underline{\dot{u}}_n + \Delta t \left((1 - \gamma_{\mathsf{H}}) \underline{\ddot{u}}_n + \gamma_{\mathsf{H}} \underline{\ddot{u}}_{n+1} \right)$$

Choice of integration parameters:

- Explicit: Stability depends on mesh size, material parameters makes just sense for piezoelectic-structure interaction
 explicit/implicit splitting
- Implicit: $\beta_{\rm H} = 0.25$, $\gamma_{\rm H} = 0.5$ 2nd order accurate

Algebraic Solver (I)



Algebraic Solver (II)

- **GMRES-solver** (General Minimal Residual)
- ILDL(k)-preconditioner (Incomplete LDL-decomposition with fill-in level k)



Algebraic Solver (III)

Dependency of iteration number on problem size



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State of the Art

• Test samples with special geometries: (IEEE Standard)

Simplification to the one-dimensional case, direct relation between resonance frequencies and coefficients

• Example: thickness resonantor





Identification of Material Parameters by Simulation of the Full System



Equipment for characterization of linear and nonlinear material properties

Impedance / gainphase analyzer







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Measurement setup

Automated setup for impedance measurement

V0

Contacting phase

- X-positioning of the spring contact pair Lc-Lp for contact force
- Testing contact resistance with constant current



sample

Measuring sequence

- Contacting phase for the short/open circuit
- Measurement for calibration
- Contacting phase for the piezo sample
- Material measurement (V0=1Veff)

Material configuration

Bulk samples

- PZT disc (radial and thickness mode)
 thickness: 0.43 mm, radius: 6.35 mm
- PZT strip (transversal mode)
- thickness: 0.43 mm, length: 11.03 mm, width: 2.44 mm

not within the IEEE range because width > 5 * thickness is not fulfilled

Device sample: stack actuator of a CR-injector application





PZT disc – fitted impedance curves





Results (3)



Stack actuator (based on results of raw material)



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Medical diagnostic, nondestructive testing



• Surface acoustic wave devices (mobile phones, television)



Origin: Siemens

Puls compression filter
 (43 MHz)

Resonator (1 GHz)





Sensor for wheel pressure

• High intensity ultrasound: e.g. lithotripsy



• High intensity ultrasound: e.g. cleaning



• Stack actuators (common-rail injection systems)



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Thank you for your attention